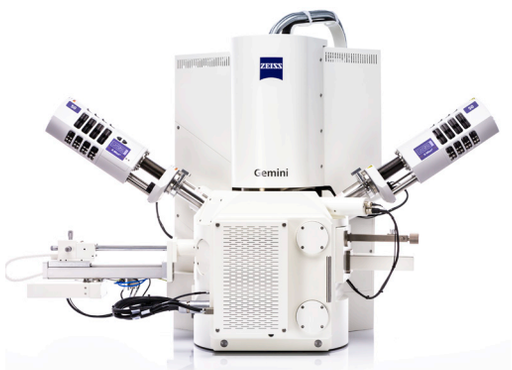
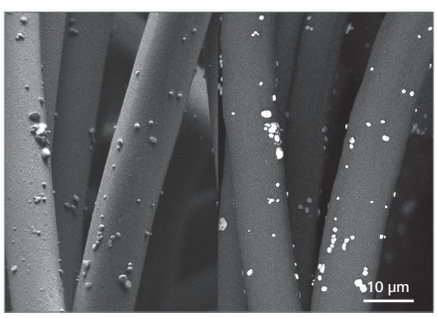
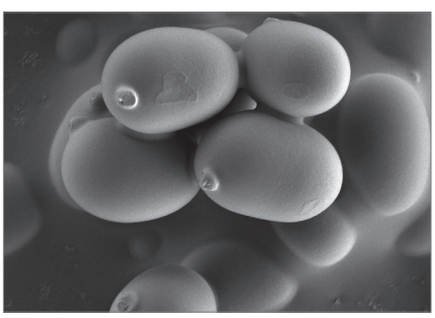
ZEISS Sigma Family

Your FE-SEMs for High Quality Imaging & Advanced Analytical Microscopy





Fibers with embedded silver, imaged at 1 kV at high vacuum, InLens Duo SE (left), InLens Duo BSE (right).



Mushroom spores imaged at 1 kV at high vacuum. These delicate, fragile structures can be imaged easily with Sigma 500 at low voltage.

Combine field emission SEM (FE-SEM) technology with advanced analytics. Profit from proven Gemini electron optics. Choose from a variety of detector options: you can image particles, surfaces, and nanostructures.
Save time with Sigma's semi-automated 4-step workflow: Structure your image and analysis routines and increase productivity. ZEISS SmartSEM Touch for Sigma 300 makes routine analysis straightforward and easy through its contemporary touch interface and a variety of automated tools.

Sigma 300 delivers excellence in price and performance. Achieve your elemental analysis fast and convenient with Sigma 500's best-in-class EDS geometry. Count on accurate, reproducible results – from any sample, every time.

Automate and Speed up Your Workflow

Control all the functionality of your Sigma with an easy 4-step workflow. Benefit from fast time-to-image and save time on training.

- Navigate your sample and then set optimal imaging conditions.
- Automatically acquire images across multiple samples utilizing regions of interest (ROIs).
- Get contextual visualization of your results.

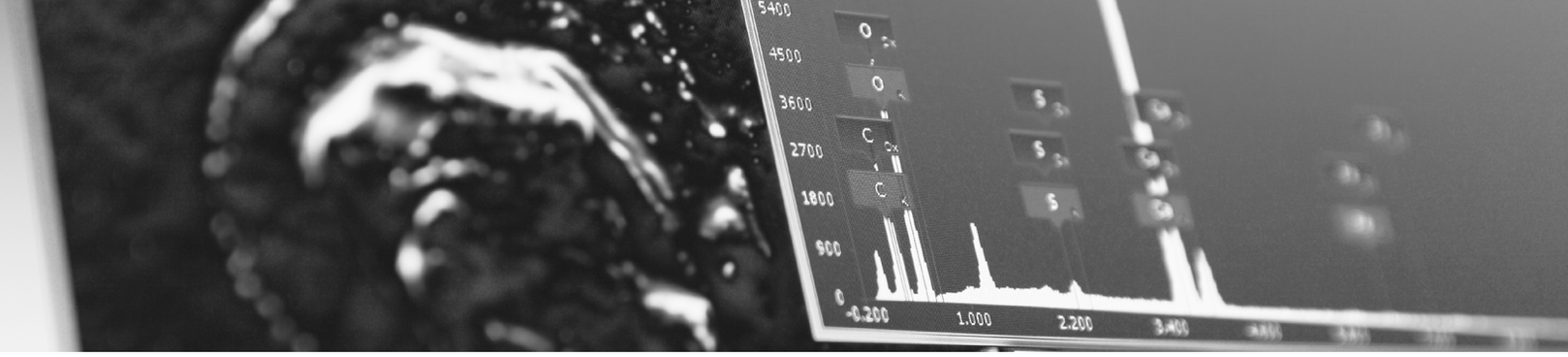
Perform Advanced Analytical Microscopy

- Combine scanning electron microscopy and elemental analytics: Sigma's best-in-class EDS geometry increases your analytical productivity, especially on beam sensitive samples.
- Get analytical data at half the probe current and twice the speed.
- Achieve complete, shadow-free analytics in your FE-SEM. Profit from using a short analytical working distance of 8.5 mm and a take-off angle of 35°.

Flexible Detection for Clear Images

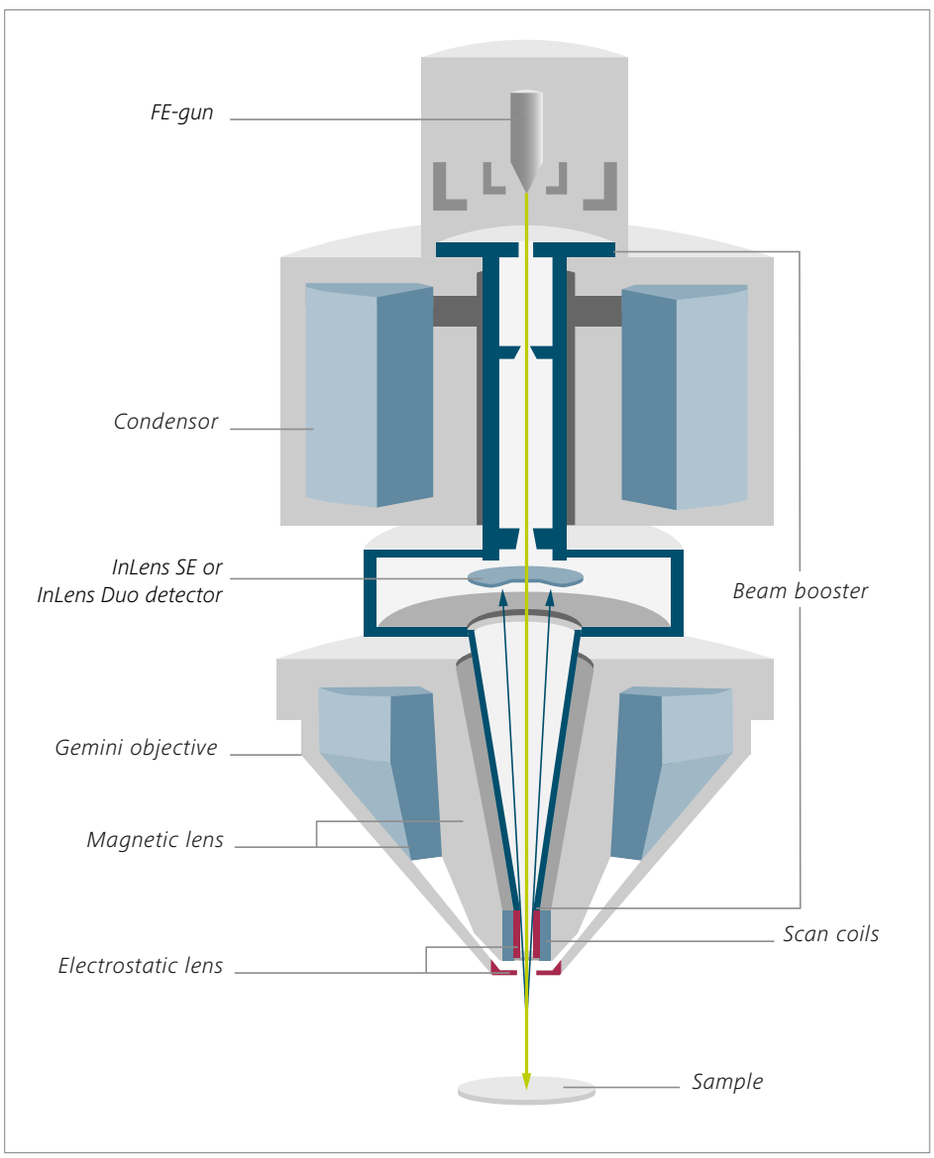
- Characterize all of your samples with the latest detection technology.
- Get topographical, high resolution information with the novel ETSE and the InLens detector for high vacuum mode.
- Obtain crisp images in variable pressure mode with the VPSE or the C2D detector.
- Produce high resolution transmission images with the aSTEM detector.
- Investigate composition with the HDBSD or the YAG detector.

ZEISS



ZEISS Sigma Family

Your FE-SEMs for High Quality Imaging & Advanced Analytical Microscopy



Based on Proven Gemini Technology

- The Gemini objective lens design combines electrostatic and magnetic fields to maximize optical performance while reducing field influences at the sample to a minimum. This enables excellent imaging, even on challenging samples such as magnetic materials.
- The Gemini in-lens detection concept ensures efficient signal detection by detecting secondary (SE) and/or back-scattered (BSE) electrons minimizing time-to-image.
- Gemini beam booster technology guarantees small probe sizes and high signal-to-noise ratios.

microscopy@zeiss.com
www.zeiss.com/sigma